

**ABSTRACT****METHOD FOR MANUFACTURING A SUBSTRATE**

The invention relates to a method for manufacturing a substrate, comprising the following steps: (a) providing a support substrate (10) with a first coefficient of thermal expansion, having on one of its faces a first plurality of parallel trenches (13) extending in a first direction, and a second plurality of parallel trenches (13) extending in a second direction; (b) transferring a useful layer (31) from a donor substrate (30) to the support substrate (10), the useful layer (31) having a second coefficient of thermal expansion; the manufacturing method being characterised in that an intermediate layer is intercalated between the front face (11) of the support substrate (10) and the useful layer (31), the intermediate layer (20) having a coefficient of thermal expansion between the first and second coefficients of thermal expansion.

Fig. 3